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Total No. of Printed Pages: [1]

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**B. Tech ECE (Semester –7<sup>th</sup>)**

**VLSI TECHNOLOGY**

**Subject Code: BECED1-731**

**Paper ID: [18111339]**

**Time: 03 Hours**

**Maximum Marks: 60**

**Instruction for candidates:**

1. Section A is compulsory. It consists of 10 parts of two marks each.
2. Section B consist of 5 questions of 5 marks each. The student has to attempt any 4 questions out of it.
3. Section C consist of 3 questions of 10 marks each. The student has to attempt any 2 questions.

**Section – A**

**(2 marks each)**

Q1. Attempt the following:

- a) Define NMOS and CMOS IC technology.
- b) What is 'bipolar IC fabrication'?
- c) Explain the need of accelerated test model in VLSI.
- d) Discuss molecular beam epitaxial technology.
- e) Discuss the oxidation technique and system in VLSI.
- f) What is the diffusion coefficient of a semiconductor?
- g) Differentiate between Latches and Flip-Flops.
- h) Define scattering phenomenon.
- i) What is 'What is Fick's law of diffusion'?
- j) Define the term Lithography.

**Section – B**

**(5 marks each)**

- Q2. Describe the thermodynamics of vapor phase growth.
- Q3. What are the techniques of multilevel metallization?
- Q4. Define Etching. Explain basic regimes of plasma etching.
- Q5. Discuss plasma assisted deposition technique.
- Q6. The yield of a VLSI chip depends on its parametric as well as functional sensitivity to the various kinds of defects, Discuss.

**Section – C**

**(10 marks each)**

- Q7. What are the various problems and concerns in Ion implantation system?
- Q8. Describe the process of Silicon shaping and Wafer preparation.
- Q9. Explain how VLSI assembly technologies cover the basic assembly operations for VLSI devices.